

APPARATUS HAVING PLATFORMS POSITIONED FOR PRECISE CENTERING
OF SEMICONDUCTOR WAFERS DURING PROCESSING

Abstract of the Disclosure

Apparatus for processing multiple semiconductor
5 wafers, includes a transfer chamber, a first processing
chamber mounted in fixed relation to the transfer chamber
and having a first wafer-holding platform with a center, a
second processing chamber mounted in adjustable relation to
the transfer chamber and to the first chamber and having a
10 second wafer-holding platform with a center, and a robot
rotatably mounted within the transfer chamber and having
first and second wafer-holding arms spaced parallel to each
other for inserting a pair of wafers simultaneously into
the first and second chambers and for placing the wafers
15 accurately centered over the respective platforms. The
spacing of the platform centers is adjusted relative to the
spacing of the robot arms such that the wafers are centered
and placed with a preselected degree of accuracy onto the
respective platforms for efficient processing of the
20 wafers.

09755516-010401